

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Application Serial No. .... 10813543  
Filing Date ..... March 3, 2004  
Confirmation No. .... 8087  
Inventor ..... Gealy, F. Daniel  
Assignee ..... Micron Technology, Inc.  
Group Art Unit ..... 1792  
Examiner ..... Chen, Keath T.  
Attorney's Docket No. .... MI22-3685  
Title: ..... Method for Reducing Physisorption During Atomic Layer Deposition

**RESPONSE TO APRIL 1, 2008 OFFICE ACTION**

To:           Mail Stop Amendment  
              Commissioner for Patents  
              P.O. Box 1450  
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